

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

Gregory BREYTA et al.

Confirmation No.: 1035

Serial No.: 10/729,453

Group Art Unit: 1713

Filing Date: December 4, 2003

Examiner: Unassigned

Title: PRECURSORS TO FLUOROALKANOL-CONTAINING OLEFIN MONOMERS,

AND ASSOCIATED METHODS OF SYNTHESIS AND USE

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

This is an Information Disclosure Statement submitted for the Examiner's consideration. Applicants respectfully request that the Examiner review and make of record the references identified below.

A PTO-1449 form listing the references accompanies this paper. Applicants would appreciate the Examiner's initialing and returning the form to indicate that the references have been reviewed and made of record. The references are as follows:

U.S. PATENT DOCUMENT					
Document No.	Issue Date or Publication Date	Name of Patentee or Applicant			
3,444,148	5/13/69	Adelman			

F	OREIGN PATENT DOCUMENTS	
Document No.	Publication Date	Country
WO 01/86352	11/15/01	PCT
WO 02/079287	10/10/02	PCT
WO 03/040827	5/15/03	PCT

NONPATENT DOCUMENTS

BAE et al. (2003), "Rejuvenation of 248 nm Resist Backbones for 157 nm Lithogrpahy," Journal of Photopolymer Science and Technology 14(4):613-620.

FEDYNYSHYN et al. (2001), "High Resolution Fluorocarbon Based Resist for 157-nm Lithography," Advances in Resist Technology And Processing XVIII, Proceedings of SPIE 4345:296-307.

ITO et al. (2001), "Polymer Design for 157 nm Chemically Amplified Resists," Advances In Resist Technology And Processing XVIII, Proceedings Of SPIE 4345:273-284.

KUNZ et al. (2001), "Experimental VUV Absorbance Study of Fluorine-Functionalized Polystyrenes," *Advances in Resist Technology and Processing XVIII, Proceedings of SPIE* 4345:285-295.

URRY et al. (1968), "Multiple Multicenter Reactions of Perfluoro Ketones with Olefins," *The Journal of Organic Chemistry* 33(6):2302-2310.

As the subject application was filed after June 30, 2003, copies of the U.S. patents disclosed in this Information Disclosure Statement are not required and, therefore, are not included.

This Information Disclosure Statement is not intended as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that any of the above references constitutes prior art to the present application within the meaning of 35 USC § 102.

As applicants have not yet received a first Action on the merits, no fee is required for filing this Information Disclosure Statement. If, however, the PTO finds that for some reason a fee is found to be necessary, our Deposit Account No. 18-0580 may be charged therefor.

Respectfully submitted,

By:

Dianne E. Reed

Registration No. 31,292

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10/729,453

December 4, 2003

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PTO/SB/21 (08-03)
Approved for use through 08/30/2003. OMB 0651-0031
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Application Number

Filing Date

TRANSMITTAL FORM

1 OIN		First Named Inventor	Gregory BRETTA	et al.		
(to be used for all correspondence after	initial filina)	Art Unit	1713			
		Examiner Name	Unassigned			
Mail Stop		Attorney Docket Number	ARC920030074US	61		
	ENCLOSU	JRES (Check all that apply				
No fee due Fee Transmittal Fee(s) due Fee Transmittal Check for \$* Charge any underpayment or credit any overpayment to Deposit Account No. 09-0441 Return postcard Amendment/Reply After Final Affidovite/deplayment(s)		Licensing-related Papers to a Technology Co		nmunication to Board and Interferences nmunication to TC e, Brief, Reply Brief) Information er ssure(s) (please		
under 37 CFR 1.52 or 1.53						
SIGN	NATURE OF A	PPLICANT, ATTORNEY, O	R AGENT			
	nne E. Reed, R d & Eberle LL	Registration No. 31,292	Telephone	(650) 330-0900		
Signature	ann	Eller	Date	3/22/04		
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I hereby certify that this correspondence is bei envelope addressed to: Commissioner for Par	ng deposited with	the United States Postal Service w	ith sufficient postage as fi	rst class mail in an		
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Signature	MAM	M	Date	4.22.04		
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Substitute	for form	1449A	/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

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Complete if Known			
Application Number	10/729,453		
Filing Date	December 4, 2003		
First Named Inventor	Gregory BREYTA et al.		
Art Unit 1713			
Examiner Name	Unassigned		
Attorney Docket Number	ARC920030074US1		

	U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No.	Document No.	Issue Date or Publication Date	Name of Patentee or Applicant of Cited Document	Class	Subclass	Filing Date if Appropriate
	AA	3,444,148	5/13/69	Adelman			

	FOREIGN PATENT DOCUMENTS								
Examiner Initials*	Cite No.	Foreign Patent Document No.	Publication Date	Country	Class	Subclass	Т		
	AB	WO 01/86352	11/15/01	PCT					
	AC	WO 02/079287	10/10/02	PCT					
	AD	WO 03/040827	5/15/03	PCT					

		OTHER DOCUMENTS — NONPATENT LITERATURE DOCUMENTS	
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), Title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	Т
	AE	BAE et al. (2003), "Rejuvenation of 248 nm Resist Backbones for 157 nm Lithogrpahy," <i>Journal of Photopolymer Science and Technology</i> 14(4):613-620.	i
	AF	FEDYNYSHYN et al. (2001), "High Resolution Fluorocarbon Based Resist for 157-nm Lithography," Advances in Resist Technology And Processing XVIII, Proceedings of SPIE 4345:296-307.	
	AG	ITO et al. (2001), "Polymer Design for 157 nm Chemically Amplified Resists," Advances In Resist Technology And Processing XVIII, Proceedings Of SPIE 4345:273-284.	
	AH	KUNZ et al. (2001), "Experimental VUV Absorbance Study of Fluorine-Functionalized Polystyrenes," Advances in Resist Technology and Processing XVIII, Proceedings of SPIE 4345:285-295.	
	ΑI	URRY et al. (1968), "Multiple Multicenter Reactions of Perfluoro Ketones with Olefins," <i>The Journal of Organic Chemistry</i> 33(6):2302-2310.	

Examiner	<u> </u>	Date	
Signature		Considered	

^{*}EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.